ABSOLUTE CONFIDENCE IN YOUR TEST- AND MEASUREMENT EQUIPMENT AND DATA

Kistler – Accredited calibrations worldwide



0.0

www.kistler.com

Content

| Kistler worldwide calibration services | 4 |
|---|-----|
| Accredited Kistler calibration laboratories: locations, measured variables and measuring ranges of permanent laboratories | 7 |
| Kistler calibration laboratories with accreditati for on-site calibrations: measurands and | ion |
| measuring ranges | 12 |
| Accredited measurands and measuring ranges: Kistler calibration laboratories | 13 |

Kistler worldwide calibration services

Kistler is the world market leader in dynamic measurement technology. Quality and maximum precision are our goals - for the high-tech products we manufacture as well as for our customer-oriented services

In metrology, traceable calibrations are the basis for precise measurements. Kistler offers a comprehensive range of calibration services tailored to the specific needs of its customers.

Kistler calibration services are available at Tech Centers, technical offices and production companies around the world. We also offer on-site and local calibrations to minimize your logistics efforts. Customers benefit from calibration services that are traceable to national or international standards, with short delivery times and low shipping costs.

Request a quote!

You can rely on our specialists to find the best solution for your specific calibration requirements.

Calibrations create added value

Calibrations provide you with feedback on the metrological behavior of a measuring device.

Your benefits from Kistler calibration services:

- Expertise: decades of calibration experience
- Calibration also possible for third-party products
- One hand solutions

The precision and stability of the measuring devices can only be ensured by monitoring by periodical calibrations. This ensures controlled processes in production. Periodical calibration creates the basis for reliable measurement results. Traceable calibrations stand for a high and accepted standard.

After a second or third calibration, ideally carried out by the same calibration service provider, confidence in the device can also be backed up by data.

This creates the basis for further decisions on topics such as recalibration intervals. All measuring devices are exposed to environmental influences throughout their service life. Wear, overloading or shock loads can damage the devices or change their properties. These events can falsify the measured values. The users of the measuring device are often unaware of the resulting problems.

For these reasons, periodic calibrations are essential to ensure that your measuring devices work accurately and reliably

Why are calibrations necessary ?

- Industrial standards (e.g. ISO 9001, IATF 16949) request periodical calibrations
- Calibrated measuring equipment is the basis for precise measurements
- Calibration provides proof that the measuring devices are accurate and reliable.





Accredited calibrations - your advantages:

- International acceptance
- Meets industrial requirements (e.g. IATF 16949)
- Performed by ISO 17025 accredited laboratories
- On-site and in-situ calibration
 available

Traceable calibration, performed by our ISO 17025 accredited laboratories

Kistler - your accredited partner for calibrations - worldwide

Decreasing measurement

uncertainty

Calibration results are accepted worldwide only if traceable to a national standard. Kistler has a worldwide network of accredited calibration laboratories for many parameters. Traceable (accredited) calibrations are offered in many measurands and ranges.

We offer our calibration services in stationary laboratories as well as on-site for many measurands.

We also offer a wide range of service calibrations for requests outside the scope of our accreditation.

Traceable calibrations

Traceable calibrations are performed by laboratories accredited according to ISO 17025. This standard implements the definitions and specifications of the International Dictionary of Metrology (VIM) and ensures the quality of laboratory services.

A calibration is basically defined as a recording of measured values with the associated measurement uncertainty. A calibration records the measured values and records them on the calibration certificate together with the respective measurement uncertainties.

Only a traceable calibration by an accredited laboratory guarantees metrological verification traceable to national standards



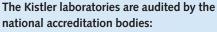
National

standard

Reference standard

Working/factory standard

Reference standards for accredited







On-site calibration

On-site calibrations are a solution, especially for measuring systems that are very large or heavy and difficult to send to a permanent calibration laboratory. Kistler is accredited to perform on-site calibrations for many measurands.

In-situ calibration

In-situ calibrations can be carried out to meet special requirements and if the measurement setup must not be dismantled (e.g. for medical applications).

In-situ calibrations are calibrations in the installed state of a transducer. An in-situ calibration can also be useful if, for technical reasons or downtimes due to time-consuming dismantling are to be minimized.



Test- and measurement equipment management

Do you need support in answering questions and making decisions about calibrations and equipment management? Do you need help with the variety of applicable standards and regulations?

- Why calibration?
- How often must be calibratet
- How shall calibration intervall detemined?
- Calibration of measurement chains or single sensors?
- Traceable- or service calibration?

Kistler will be happy to advise you on the answers to these and other questions and help you set up a management system for your test and measurement equipment that ensures audit compliance. Contact us - our experts will support you! service@kistler.com

Accredited Kistler calibration laboratories: locations, measured variables and measuring ranges of permanent laboratories

Germany

Calibration laboratory Kistler Remscheid GmbH

| Measurand/Unit under test | | Range | |
|--|----------|-------|----------|
| Angle of rotation Direct angle transducer Indirect angle systems | 0° | to | 360° |
| Torque | | | |
| Torque sensors and torque | 0.01 N·m | to | <0.1 N·m |
| measuring equipment | 0.1 N·m | to | <1 N·m |
| | 1 N⋅m | to | 1 kN⋅m |
| | >1 kN·m | to | 2 kN⋅m |
| | >2 kN·m | to | 20 kN∙m |
| Transfer torque uronches | 0.1 N⋅m | to | <1 N·m |
| Transfer torque wrenches | 1 N⋅m | to | 1 kN∙m |
| Torque wrench calibration | 0.2 N⋅m | to | <2 N⋅m |
| systems | 2 N⋅m | to | 3 kN∙m |
| | 0.01 N·m | to | <1 N·m |
| Manual operated torque tools | 1 N⋅m | to | <5 N·m |
| LUUIS | 5 N∙m | to | 1.5 kN∙m |
| Force | | | |
| Force sensors and measuring equipment | 2 kN | to | 500 kN |

Calibration laboratory Kistler Instrumente GmbH, Lorch

| Measurand/Unit under test | R | ange | |
|---------------------------|-----------|------|----------|
| Torque | 0.004 N·m | to | 0.01 N·m |
| Torque sensors and | >0.01 N·m | to | <0.1 N·m |
| torque measuring chains | 0.1 N⋅m | to | 20 N∙m |
| | 0,1 N·m | to | <0,2 N·m |
| | 0.2 N⋅m | to | <0.4 N·m |
| | 0.4 N⋅m | to | <1 N·m |
| | 1 N·m | to | 200 N·m |
| | 1 N⋅m | to | 10 N∙m |
| | >10 N·m | to | 3 kN∙m |
| | 1 N⋅m | to | 5 N⋅m |
| | >5 N·m | to | 10 N∙m |
| | >10 N·m | to | 20 N∙m |
| | >20 N⋅m | to | 5 kN∙m |
| | 1 kN·m | to | 20 kN∙m |
| | >20 kN·m | to | 100 kN∙m |

Calibration laboratory Kistler ATD Heidelberg

| Measurand/Unit under test | | Rang | e |
|--|----------------------|------|------------------------|
| Acceleration Acceleration transducers and measuring chains | 200 m/s ² | to | 2 000 m/s ² |
| Force Force sensors | 0,5 kN | to | 50 kN |
| Multicomponent force and torque | 0,5 kN | to | 50 kN |
| Multicomponent transducers (ATD) | 2 N⋅m | to | 1 400 N⋅m |
| Length | 0 mm | to | 200 mm |
| Displacement sensors | >200 mm | to | 600 mm |
| | >600 mm | to | 850 mm |



Calibration laboratory Kistler Instrumente GmbH Sindelfingen

| Measurand/Unit under test | easurand/Unit under test Range | | | |
|--|--------------------------------|----|----------------------|--|
| Acceleration | 1 | ta | $90 m/c^{2}$ | |
| Accelerometers, acceleration measuring chains (reference | 1 m/s ² | to | 80 m/s ² | |
| frequency range) | 10 m/s ² | to | 200 m/s ² | |
| Acceleration sensors Acceleration measuring chains | 5 m/s² | to | 200 m/s ² | |
| (medium frequency range) | J 11/3- | | 200 11/3- | |
| Accelerometers Accelerometers (low-frequency range) | 0,1 m/s ² | to | 80 m/s² | |
| Vibration calibrator | 1 m/s ² | to | 20 m/s ² | |
| Frequency | 10 Hz | to | 160 Hz | |
| | >160 Hz | to | <1 kHz | |
| | 1 kHz | to | <5 kHz | |
| | 5 kHz | to | <9 kHz | |
| | 9 kHz | to | 10 kHz | |
| Distortion | 10 Hz | to | 10 kHz | |
| Voltage Voltage measuring amplifier with grounded input and differential input, ICP-Measuring amplifier with constant current supply | 70 mV | to | 30 V | |
| Charge Charge amplifier with grounded input and differential input | 7 pC | to | 10 nC | |
| Pressure | 1 bar | to | | |
| Absolute pressure p _{abs} | 3 bar | to | 401 bar | |
| | >401 bar | to | 1 401 bar | |
| | 0 bar | to | 20 bar | |
| Positive pressure p_e | 0 bar | to | | |
| | 2 bar | to | 400 bar | |
| | >40 bar | to | 1 400 bar | |
| | 0 bar | to | 20 bar | |
| Force | 0.01 N·m | to | <0.1 N·m | |
| Force sensors | 0.1 N∙m | to | <1 N·m | |
| | 1 N·m | to | 1 kN∙m | |
| | >1 kN·m | to | 2 kN⋅m | |
| | >2 kN·m | to | 20 kN∙m | |
| Multicomponent Force and torque | 0.1 N·m | to | <1 N·m | |
| 1 | 1 N·m | to | 1 kN∙m | |
| Multicomponent sensors | 0.2 N⋅m | to | <2 N·m | |
| | 2 N⋅m | to | 3 kN∙m | |
| Length Length sensors | 2 mm | to | 500 mm | |

Calibration laboratory Kistler Instrumente GmbH München

| Measurand/Unit under test | | Range | |
|---------------------------|---------|-------|---------|
| DC voltage | 0 V | to | 1 mV |
| DC sources | >1 mV | to | 10 mV |
| | >10 mV | to | 100 mV |
| | >100 mV | to | 1 V |
| | >1 V | to | 10 V |
| | >10 V | to | 20 V |
| | >20 V | to | 100 V |
| | >100 V | to | 1 000 V |
| DC voltage | 0 V | to | 450 µV |
| Measuring systems | >450 µV | to | 3 mV |
| | >3 mV | to | 4.5 mV |
| | >4.5 mV | to | 10 mV |
| | >10 mV | to | 30 mV |
| | >30 mV | to | 45 mV |
| | >45 mV | to | 300 mV |
| | >300 mV | to | 450 mV |
| | >450 mV | to | 3 V |
| | >3 V | to | 4.5 V |
| | >4.5 V | to | 30 V |
| DC current | 0 A | to | 100 µA |
| Sources | >100 µA | to | 1 mA |
| | >1 mA | to | 10 mA |
| | >10 mA | to | 100 mA |
| | >100 mA | to | 1 A |
| | >1 A | to | 3 A |
| | 1 mA | to | 20 mA |
| DC resistance | 0 Ω | to | 100 Ω |
| Resistance | >100 mΩ | to | 1 Ω |
| | >1 Ω | to | 10 Ω |
| | >10 Ω | to | 100 Ω |
| | >100 Ω | to | 250 Ω |
| | >250 Ω | to | 660 Ω |
| | >660 Ω | to | 1 kΩ |
| | >1 kΩ | to | 10 kΩ |
| | 10kΩ | to | 100 kΩ |
| | >100 kΩ | to | 1 MΩ |

Switzerland

Calibration laboratory Kistler Winterthur AG

| Measurand/Unit under test | | Rang | e |
|---|---------------|----------|------------------------|
| Fluid overpressure | 1 bar | to | - 10 ba |
| Piezoelectrical pressure | 10 bar | to | <100 bar |
| sensor calibration | 100 bar | | < 100 bar 1 000 bar |
| | 1 000 bar | to | |
| | 0 bar | to to | 8 000 bar <5 bar |
| Piezoresistive pressure sensor calibration | 5 bar | to | <50 bar |
| | 50 bar | to | 1 000 bar |
| | 1 000 bar | to | 5 000 bar |
| Force | 0.05 kN | | |
| Piezoelectric force sensor | 0.05 kN | to to | <2 kin 50 kN |
| calibration | 2 kin 1 kN | to | 100 kN |
| | 1 kN | | <50 kN |
| | 50 kN | to | <50 kN |
| Chargo | | to | |
| Charge Generation and calibration | 1 pC | to | <20 pC |
| | 20 pC | to | <50 pC |
| | 50 pC | to | <200 pC |
| | 200 pC | to | <48 000 pC |
| | 48 nC | to | 3 100 nC |
| Voltage (DC) | 0 V | to | <0.12 V |
| | 0.12 V | to | <1.2 V |
| | 1.2 V | to | <12 V |
| | 12 V | to | 100 V |
| Voltage (AC) | 0 V | to | <0.12 V |
| | 0.12 V | to | <1.2 V |
| | 1.2 V | to | <12 V |
| | 12 V | to | 30 V |
| | 0 Vpp | to | <0.33 Vpp |
| | 0.33 Vpp | to | <3.3 Vpp |
| | 3.3 Vpp | to | <33 Vpp |
| | 33 Vpp | to | 85 Vpp |
| Current (DC) | 0 mA | to | <0.37 mA |
| | 0.37 mA | to | <1.4 mA |
| | 1.4 mA | to | <4.5 mA |
| | 4.5 mA | to | <144 mA |
| | 144 mA | to | 1 000 mA |
| Resistance (DC) | 0.01 Ω | to | <12 Ω |
| | 12 Ω | to | <120 Ω |
| | 0.12 kΩ | to | <1.2 kΩ |
| | 1.2 kΩ | to | <12 kΩ |
| | 12 kΩ | to | <120 kΩ |
| | 0.12 MΩ | to | <1.2 MΩ |
| | 1.2 MΩ | to | <12 MΩ |
| | 12 MΩ | to | 120 MΩ |

| Measurand/Unit under test | F | Range | |
|---------------------------|--------|-------|-----------|
| Capacity | 1 pF | to | <1000 pF |
| | 1 nF | to | <100 nF |
| | 100 nF | to | <1 000 nF |
| | 1 pF | to | <10 pF |
| | 10 pF | to | <100 pF |
| | 100 pF | to | <1 000 pF |
| | 1 nF | to | <10 nF |
| | 10 nF | to | <100 nF |
| | 100 nF | to | 1 000 nF |

United Kingdom

Permanent calibration laboratory Kistler Instruments Ltd., Hook

| Measurand/Unit under test | | Range | e |
|-------------------------------------|---------|-------|---------|
| Charge, DC, 100 Hz & 1 kHz | | | |
| Nominal set points | 100 pC | | |
| at full range | 1 nC | | |
| | | 10 nC | |
| | 1(| 00 nC | |
| | | 1 µC | |
| | | 2 μC | |
| Range values | 2 pC | to | 10 pC |
| 500 mV to 10 V | 10 pC | to | 100 pC |
| | 100 pC | to | 1 nC |
| | 1 nC | to | 10 nC |
| | 10 nC | to | 100 nC |
| | 100 nC | to | 1 µC |
| | 200 nC | to | 2 µC |
| All range values | 2 pC | to | 10 pC |
| | 10 pC | to | 100 pC |
| | 100 pC | to | 1 nC |
| | 1 nC | to | 10 nC |
| | 10 nC | to | 100 nC |
| | 100 nC | to | 1 µC |
| | 200 nC | to | 2 µC |
| DC voltage | 100 mV | to | 200 mV |
| Zero volts | 200 mV | to | 10 V |
| | | | |
| | 100 mV | to | 200 mV |
| | 200 mV | to | 10 V |
| Voltage Current resistance | | | |
| ratio piezo resistive amplifiers | 10 Ω | to | 1000 Ω |
| Excitation current | 1 mA | to | 4 mA |
| Pressure | | | |
| Continuous calibration | 10 MPa | to | 100 Mpa |
| of piezoelectric pressure sensors | 100 MPa | to | 800 MPa |

USA

Calibration laboratory Amherst, NY/Novi, MI

| Measurand/Unit under test | | Dan | 7 0 |
|--|--------------|----------|--------------|
| Acoustics and vibration | | Ran | ge |
| Vibration | | | |
| Magnitude/Frequency | 5 mV | to | 4 V/gn |
| 0.5 Hz to 20 Hz | | | |
| Vibration, | | | |
| Magnitude & Charge/ | | | |
| Frequency response | | | |
| 10 Hz to 2 000 Hz | 5 mV | to | 4 V/gn |
| >2 000 Hz to 10 000 Hz | 0.1 pC | to | 100 pC/gn |
| >10 000 Hz to 15 000 Hz | 0.1 pc | 10 | 100 p 0/81 |
| >15 000 Hz to 17 000 Hz | | | |
| >17 000 Hz to 20 000 Hz | | | |
| Vibration, rotational | | | |
| (magnitude) | | | 12.5 Hz |
| Electrical – DC/low frequency | , | | |
| Charge (automated) | 1.6 pC | to | 90 000 pC |
| Charge (manual) | 5 pC | to | 2 000 000 pC |
| Charge | ±10 | 0 pC | |
| (automated) | ±1 00 | 0 pC | |
| | ±10 00 | • | |
| | ±100 00 | • | |
| | ±1 000 00 | • | |
| DC Voltage – source | -10 V | to | 10 V |
| | -10 V | | 10 V |
| DC Voltage – measure | | to | |
| Gain accuracy | 0.5 | to | 150 |
| Gain accuracy | 1x, 10x, 100 | JX | |
| Mass and mass related | | | |
| Force, dynamic (voltage sensitivity) | 0.04 lbf | to | 5 lbf |
| Force, impulse (sensitivity at 100 Hz) | 100 lbf | to | 5 000 lbf |
| Force, static (voltage, charge sensitivity) | 50 lbf | to | 50 000 lbf |
| Pressure | –14.5 psi | to | <0 psi |
| Absolute | >0 psi | to | 500 psi |
| Pressure Sinusodial | 50 psi | to | 1 000 psi |
| Pressure, static | 20 psi | to | 15 000 psi |
| | 5 000 psi | to | 100 000 psi |
| Pressure, pneumatic | | to | · · · |
| Gage/absolute | –14.5 psi | to to | <0 psi |
| Current: 4 mA to 20 mA | >0 psi | to | 1 500 psi |
| Pressure, pneumatic | –14.5 psi | to | <0 psi |
| Gage/absolute | >0 psi | to | 1 500 psi |
| Voltage: up to 10 V | | | |

| Measurand/Unit under test | | Ran | σe |
|---|------------|-------|---------------------|
| Pressure, hydraulic | | Truen | 5° |
| Current: 4 mA to 20 mA | 500 psig | to | 5 000 psig |
| Pressure, hydraulic Voltage: up to 10 V | 500 psig | to | 6 000 psig |
| Pressure, hydraulic | 0 bar | to | 700 bar |
| Voltage: up to 10 V Acoustics and vibration | | | |
| | | | |
| Vibration Magnitude/ Frequency response | | | |
| 3 Hz to 8 Hz >8 Hz to 16 Hz | 0.04 mV | to | 4 V/gn at 100 Hz |
| >16 Hz to 1 000 Hz >1 000 Hz to 5 000 Hz >5 000 Hz to 10 000 Hz | 0.1 pC | to | 100 pC/gn |
| Electrical – DC/low frequency | | | |
| DC voltage – source | –10 V | to | 10 V |
| DC voltage – measure | –10 V | to | 10 V |
| - | 0 V | to | 20 V |
| Charge | 2 pC | to | 2 100 000 pC |
| Charge | ±100 | рC | <u> </u> |
| (automated) | ±1 000 | рC | |
| | ±10 000 | • | |
| | ±100 000 | • | |
| | ±1 000 000 | • | |
| Current – measure | 1 mA | to | 20 mA |
| Length – dimensional metrolo | gy | | |
| Linear displacement | 0 mm | to | 300 mm |
| Rotational displacement | 0° | to | 360° |
| Mass and mass related | | | |
| Force, static | 100 N | to | 500 N |
| | >500 N | to | 5 000 N |
| | >5 000 N | to | 500 000 N |
| | 2 200 N | to | 22 000 N |
| | >22 000 N | to | 500 000 N |
| Pressure, static | 1 bar | to | 300 bar |
| | 80 bar | to | 8 000 bar |
| Mass and mass related | 1 bar | to | 250 bar |
| Velocity | 1 kph | to | 330 kph |
| Force | 0.5 kN | to | 25 kN |
| Moment | 12.5 N·m | to | 1 000 N·m |
| Torque sensors | 2 N⋅m | to | 10 N·m |
| | 10 N·m | to | 200 N·m |
| | 50 N∙m | to | 500 N∙m |
| | 500 N∙m | to | 2kN∙m |
| | 2 kN⋅m | to | 4 kN∙m |
| | 2 kN⋅m | to | 4 kN⋅m |

Calibration laboratory Amherst, NY/Novi, MI

| Measurand/Unit under test | Ra | ange | |
|------------------------------|--------------|------|-------------|
| Torque wrenches | 2 N·m | to | 20 N·m |
| | >20 N·m | to | 500 N∙m |
| Time and frequency | | | |
| Frequency – measure | 0 Hz | to | 20 000 Hz |
| Time – measure | 0 µs | to | 150 µs |
| Angular rate | –3 000 °/sec | to | 3 000 °/sec |

China

Calibration laboratory Kistler Innovative Technology Co., Ltd., Shanghai

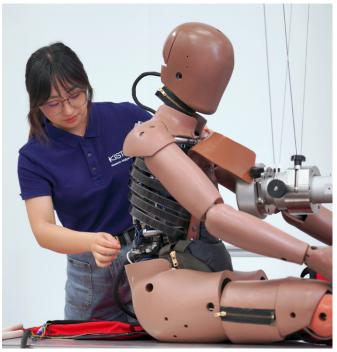
| Measurand/Unit under test | l | Range | |
|---------------------------|------|-------|--------|
| Force | 0 kN | to | 50 kN |
| Length Linear sensors | 0 mm | to | 800 mm |

Japan

Calibration laboratory Kistler Japan Co. Ltd, Shinyokohama

| Measurand/Unit under test | Range | | | | | | |
|------------------------------|---|----------|----------|--------|--|--|--|
| Acoustic | Voltage sensitivity: mV/(m/s ²) | | | | | | |
| Accelerometer | Accelerometer output $\geq 0.01 \text{ mV}$ | | | | | | |
| | | 20 Hz | to | 1 kHz | | | |
| | | 1 kHz | to | 5 kHz | | | |
| | | 5 kHz | to | 10 kHz | | | |
| | Charge sensitivity: pC/(m/s²) Accelerometer output ≥1 pC | | | | | | |
| | | 20 Hz | to | 1 kHz | | | |
| | | 1 kHz | to | 5 kHz | | | |
| | | 5 kHz | to | 10 kHz | | | |
| Mass, force and | Force | | | | | | |
| weighing devices | 100 N compression | | | | | | |
| Load cell | 200 N compression | | | | | | |
| | | 500 N | l compre | ession | | | |
| | | 1 000 N | l compre | ession | | | |
| | | 2 000 N | l compre | ession | | | |
| | | 5 000 N | l compre | ession | | | |
| | | 10 000 N | l compre | ession | | | |
| | | 20 000 N | l compre | ession | | | |
| | | 50 000 N | l compre | ession | | | |
| | Torque | | | | | | |
| | | 400 N∙rr | n compre | ession | | | |
| | | 680 N∙m | n compre | ession | | | |
| | | 900 N∙m | n compre | ession | | | |
| | | | | | | | |





Kistler calibration laboratories with accreditation for on-site calibrations: measurands and measuring ranges

On-site accreditation Kistler Remscheid GmbH

| Measurand/Unit under test | | Range | |
|--|---------|-------|---------|
| Angle of rotation Angle sensors in combination with torque | 0° | to | 360° |
| Torque | 0.2 N⋅m | to | 1 N⋅m |
| Torque measuring systems | 200 N·m | to | 60 kN∙m |
| Torque wrench calibration | 0.2 N·m | to | <2 N·m |
| systems | 2 N⋅m | to | 3 kN∙m |

On-site accreditation Kistler Instrumente GmbH Lorch

| Measurand/Unit under test | | Range | |
|--|------------------|----------|-----------------|
| Force (WPM) Force measuring systems not according to DIN 51220 | 0.5 kN >15 kN | to to | 15 kN 300 kN |



Accredited measurands and measuring ranges: Kistler calibration laboratories

| Measurand/Unit under test | | Range | | Laboratory, City, Country | | |
|--|---|----------|---|--|--|--|
| Acceleration sensors | | | | Kistler Instrumente GmbH Sindelfingen, | | |
| Acceleration measuring chains | 5 m/s ² | to | 200 m/s ² | Germany | | |
| (medium frequency range) Acceleration | | | | | | |
| Acceleration Acceleration transducers and measuring chains | 200 m/s ² | to | 2 000 m/s ² | Kistler ATD Heidelberg, Germany | | |
| Acceleration | | | | | | |
| Accelerometers, acceleration measuring chains | 1 m/s ² 10 m/s ² | to to | 80 m/s ² 200 m/s ² | Kistler Instrumente GmbH Sindelfingen, | | |
| (reference frequency range) | 10 111/5- | to | 200 111/5- | Germany | | |
| Accelerometer | | | /: mV/(m/s²) | | | |
| | | | put ≥0.01 mV | | | |
| | 20 Hz | to | 1 kHz | | | |
| | 1 kHz | to | 5kHz | | | |
| | 5 kHz | to | 10 kHz | Kistler Japan Co. Ltd, Shinyokohama, JP | | |
| | Charge sen Accelerome | - | | | | |
| | 20 Hz | to | tput ≥1 pC 1 kHz | | | |
| | 1 kHz | to | 5 kHz | | | |
| | 5 kHz | to | 10 kHz | | | |
| Accelerometers | 1 m/s ² | to | 80 m/s ² | Kietlan hastmussenta Cashili. Cin dalfia ann | | |
| Accelerometers (low-frequency range) | 10 m/s ² | to | 200 m/s ² | Kistler Instrumente GmbH, Sindelfingen, Germany | | |
| Acoustic und vibration Vibration, magnitude/frequenz (0,5 Hz to 20 Hz) | 5 mV | to | | Amherst, NY/Novi, MI, USA | | |
| Angle of rotation on-site Angle sensors in combination with torque | 0° | to | 360° | Kistler Remscheid GmbH, Germany | | |
| Angle of rotation Direct angle transducer Indirect angle systems | 0° | to | 360° | Kistler Remscheid GmbH, Germany | | |
| Angular rate | -3 000 | to | 3 000 % | Amherst, NY/Novi, MI, USA | | |
| AC Voltage | 0 V | to | <0.12 V | | | |
| AC Voltage | 0.12 V | to | <0.12 V <1.2 V | | | |
| | 1.2 V | to | <1.2 V | | | |
| | 1.2 V 12 V | to | 30 V | | | |
| | 0 Vpp | to | <0.33 Vpp | Kistler Winterthur AG, Switzerland | | |
| | 0.33 Vpp | to | <3.3 Vpp | | | |
| | 3.3 Vpp | to | <33 Vpp | | | |
| | 33 Vpp | to | 85 Vpp | | | |
| Capacity | 1 pF | to | <1000 pF | | | |
| | 1 pr 1 nF | to | <1000 pr | | | |
| | 100 nF | to | <1 000 nF | | | |
| | 1 pF | to | <10 pF | | | |
| | 10 pF | to | <100 pF | Kistler Winterthur AG, Switzerland | | |
| | 100 pF | to | <1 000 pF | | | |
| | 1 nF | to | <10 nF | | | |
| | 10 nF | to | <100 nF | | | |
| | 100 nF | to | 1 000 nF | | | |

| Charge | Range | | e | Laboratory, City, Country | | |
|--|-------------|-----|--------------|---|--|--|
| Charge | 2 pC | to | 2 100 000 pC | Amherst, NY/Novi, MI, USA | | |
| Charge (automated) | 1.6 pC | to | 90 000 pC | Amherst, NY/Novi, MI, USA | | |
| Charge | ± 100 | рС | | | | |
| (automated) | ± 1 000 | pC | | | | |
| | ± 10 000 | pC | | Amherst, NY/Novi, MI, USA | | |
| | ± 100 000 | рC | | | | |
| | ± 1 000 000 | pC | | | | |
| Charge (manual) | 5 pC | to | 2 000 000 pC | Amherst, NY/Novi, MI, USA | | |
| Charge | 2 pC | to | 10 pC | | | |
| All ranges | 10 pC | to | 100 pC | | | |
| | 100 pC | to | 1 nC | | | |
| | 1 nC | to | 10 nC | Amherst, NY/Novi, MI, USA | | |
| | 10 nC | to | 100 nC | | | |
| | 100 nC | to | 1 µC | | | |
| | 200 nC | to | 2 µC | | | |
| Charge | ± 100 | pС | . <u> </u> | | | |
| Automated | ± 1 000 | | | | | |
| | ± 10 000 | | | Amherst, NY/Novi, MI, USA | | |
| | ± 100 000 | | | | | |
| | ± 1 000 000 | | | | | |
| Charge Charge amplifier with grounded input and | 7 pC | | 10 nC | Kistler Instrumente GmbH Sindelfingen, Germany | | |
| differential input | | | | | | |
| Charge Generation and calibration | | to | <20 pC | | | |
| Generation and calibration | 20 pC | to | <50 pC | | | |
| | | to | <200 pC | Kistler Winterthur AG, Switzerland | | |
| | 200 pC | | <48 000 pC | | | |
| | 48 nC | to | 3 100 nC | | | |
| Charge | | to | 10 pC | | | |
| Range 500 mV to 10 V | | to | 100 pC | | | |
| | | to | 1 nC | | | |
| | 1 nC | to | 10 nC | Amherst, NY/Novi, MI, USA | | |
| | 10 nC | to | 100 nC | | | |
| | 100 nC | to | 1 µC | | | |
| | 200 nC | to | 2 µC | | | |
| Charge, DC, 100 Hz & 1 kHz | 10 | рC | | | | |
| Nominal set points at full range | 100 | pC | | | | |
| | 1 | nC | | | | |
| | 10 | nC | | Amherst, NY/Novi, MI, USA | | |
| | 100 | nC | | | | |
| | 1 | μC | | | | |
| | 2 | 2μC | | | | |
| and the second second | 10 MPa | to | 100 Mpa | | | |
| Continuous calibration of piezoelectric pressure | 10 1011 a | 10 | 100 mpa | A STREET NIX/NESS AND LICA | | |
| Continuous calibration of piezoelectric pressure sensors | 100 MPa | to | 800 MPa | Amherst, NY/Novi, MI, USA | | |

| Measurand/Unit under test | | Range | | Laboratory, City, Country |
|-----------------------------|--------------|-------|----------|------------------------------------|
| DC current | 0 mA | | <0.37 mA | |
| | 0.37 mA | | <1.4 mA | |
| | 1.4 mA | | <4.5 mA | Kistler Winterthur AG, Switzerland |
| | 4.5 mA | | <144 mA | |
| | 144 mA | | 1 000 mA | |
| DC current sources | 0 A | to | 100 µA | |
| | >100 µA | to | 1 mA | |
| | >1 mA | to | 10 mA | |
| | >10 mA | to | 100 mA | Kistler Instrumente GmbH München, |
| | >100 mA | to | 1 A | Germany |
| | >100 MIX | to | 3 A | |
| | 21 A 1 mA | | 20 mA | |
| DC maintaine | | to | | |
| DC resistance Resistance | 0 Ω | to | 100 Ω | |
| Resistance | >100 mΩ | to | 1Ω | |
| | >1 Ω | to | 10 Ω | |
| | >10 Ω | to | 100 Ω | |
| | >100 Ω | to | 250 Ω | Kistler Instrumente GmbH München, |
| | >250 Ω | to | 660 Ω | Germany |
| | >660 Ω | to | 1 kΩ | |
| | >1 kΩ | to | 10 kΩ | |
| | >10kΩ | to | 100 kΩ | |
| | >100 kΩ | to | 1 MΩ | |
| DC restistance | 0.01 Ω | to | <12 Ω | |
| | 12 Ω | to | <120 Ω | |
| | 0.12 kΩ | to | <1.2 kΩ | |
| | 1.2 kΩ | to | <12 kΩ | |
| | 12 kΩ | to | <120 kΩ | Kistler Winterthur AG, Switzerland |
| | 0.12 MΩ | to | <1.2 MΩ | |
| | 1.2 MΩ | to | <12 MΩ | |
| | 12 MΩ | to | 120 MΩ | |
| DC voltage – measure | -10 V | to | 10 V | |
| | 0 V | to | 20 V | Amherst, NY/Novi, MI, USA |
| DC voltage – measure | -10 V | to | 10 V | Amherst, NY/Novi, MI, USA |
| DC voltage – source | -10 V | to | 10 V | Amherst, NY/Novi, MI, USA |
| DC voltage | Zero Volts | | 10 1 | |
| Devoluge | 100 mV | to | 200 mV | |
| | 200 mV | to | 10 V | |
| | | | | Amherst, NY/Novi, MI, USA |
| | 100 mV | to | 200 mV | |
| | 200 mV | to | 10 V | |
| DC voltage – source | –10 V | | to 10 V | Amherst, NY/Novi, MI, USA |
| DC voltage | 0 V | to | 1 mV | |
| DC sources | >1 mV | to | 10 mV | |
| | >10 mV | to | 100 mV | |
| | >100 mV | to | 1 V | Kistler Instrumente GmbH München, |
| | >1 V | to | 10 V | Germany |
| | >10 V | to | 20 V | |
| | >20 V | to | 100 V | |
| | >100 V | to | 1 000 V | |

| Measurand/Unit under test | R | lange | | Laboratory, City, Country |
|---|--------------------|----------|--------------------|--|
| DC voltage | 0 V | to | 450 μV | |
| Measuring systems | >450 µV | to | 3 mV | |
| | >3 mV | to | 4.5 mV | |
| | >4.5 mV | to | 10 mV | |
| | >10 mV | to | 30 mV | Kietlen Instrumente Creht I München |
| | >30 mV | to | 45 mV | Kistler Instrumente GmbH München, Germany |
| | >45 mV | to | 300 mV | Germany |
| | >300 mV | to | 450 mV | |
| | >450 mV | to | 3 V | |
| | >3 V | to | 4.5 V | |
| | >4.5 V | to | 30 V | |
| Distortion | 10 Hz | to | 10 kHz | Kistler Instrumente GmbH Sindelfingen, Germany |
| DV voltage | 0 V | to | <0.12 V | |
| | 0.12 V | to | <1.2 V | Kictler Winterthur AC Switzerland |
| | 1.2 V | to | <12 V | Kistler Winterthur AG, Switzerland |
| | 12 V | to | 100 V | |
| Excitation current | 1 mA | to | 4 mA | Amherst, NY/Novi, MI, USA |
| | 1 bar | to | 10 bar | |
| Fluid overpressure | 10 bar | to | <100 bar | |
| Piezoelectrical pressure sensor calibration | 100 bar | to | 1 000 bar | Kistler Winterthur AG, Switzerlan |
| | 1 000 bar | to | 8 000 bar | |
| | 0 bar | to | <5 bar | |
| Fluid overpressure | 5 bar | to | <50 bar | |
| Piezoresistive pressure sensor calibration | 50 bar | to | 1 000 bar | Kistler Winterthur AG, Switzerlan |
| | 1 000 bar | to | 5 000 bar | |
| Force | 0 kN | to | 50 kN | Kistler Innovative Technology Co., Ltd., Shanghai, CN |
| Force Force sensors | 2 kN | to | 20 kN | Kistler Instrumente GmbH Sindelfingen, Germany |
| Force (WPM) on-site | 0.5 kN | to | 15 kN | Kistler Instrumente GmbH Lorch, |
| Force measuring systems not according | >15 kN | to | 300 kN | Germany |
| to DIN 51220 | | | | |
| Force Piezoelectric force sensor calibration | 0.05 kN | to | <2 kN | |
| riezoelectric force sensor calibration | 2 kN | to | 50 kN | |
| | 1 kN | to | 100 kN | Kistler Winterthur AG, Switzerland |
| | 1 kN | to | <50 kN | |
| | 50 kN | to | 500 kN | |
| Force Force sensors | 0.5 kN | to | 50 kN | Kistler ATD Heidelberg, Germany |
| Force Force sensors and measuring equipment | 2 kN | to | 500 kN | Kistler Remscheid GmbH, Germany |
| Force Moment | 0.5 kN 12.5 N⋅m | to to | 25 kN 1 000 N⋅m | Amherst, N/Novi, MN, USA |
| Force, dynamic (Voltage sensitivity) | 0.04 lbf | to | 5 lbf | Amherst, NY/Novi, MI, USA |
| Force, impulse (Sensitivity at 100 Hz) | 100 lbf | to | 5 000 lbf | Amherst, NY/Novi, MI, USA |
| Force, static (Voltage, charge sensitivity) | 50 lbf | to | 50 000 lbf | Amherst, NY/Novi, MI, USA |

| Measurand/Unit under test | | Range | | Laboratory, City, Country |
|--|-----------|----------|---------------|--|
| Force, static | 100 N | to | 500 N | |
| | >500 N | to | 5 000 N | |
| | >5 000 N | to | 500 000 N | Amherst, NY/Novi, MI, USA |
| | 2 200 N | to | 22 000 N | |
| | >22 000 N | to | 500 000 N | |
| Frequency – measure | 0 Hz | to | 20 000 Hz | Amherst, NY/Novi, MI, USA |
| Frequency | 10 Hz | to | 160 Hz | |
| | >160 Hz | to | <1 kHz | |
| | 1 kHz | to | <5 kHz | Kistler Instrumente GmbH Sindelfingen, Germany |
| | 5 kHz | to | <9 kHz | Contaily |
| | 9 kHz | to | 10 kHz | |
| Gain accuracy | 0.5 | to | 150 | Amherst, NY/Novi, MI, USA |
| Gain accurancy | | | 1x, 10x, 100x | Amherst, NY/Novi, MI, USA |
| Hydraulic pressure Current: 4 mA to 20 mA | 500 psig | to | 5 000 psig | Amherst, NY/Novi, MI, USA |
| Hydraulic pressure Voltage: up to 10 V | 500 psig | to | 6 000 psig | Amherst, NY/Novi, MI, USA |
| Hydraulic pressure Voltage: up to 10 V | 0 bar | to | 700 bar | Amherst, NY/Novi, MI, USA |
| Length – dimensional metrology | | | | Amherst, NY/Novi, MI, USA |
| Length | 0 mm | to | 200 mm | |
| Displacement sensors | >200 mm | to | 600 mm | Kistler ATD Heidelberg, Germany |
| | >600 mm | to | 850 mm | |
| Length | 0 mm | to | 200 mm | Kistlan Instruments Credul I Cindalfin son |
| Length sensors | >200 mm | to | 600 mm | Kistler Instrumente GmbH Sindelfingen, Germany |
| | >600 mm | to | 850 mm | |
| Length Linear sensors | 0 mm | to | 800 mm | Kistler Innovative Technology Co., Ltd., Shanghai, CN |
| Linear displacement | 0 mm | to | 300 mm | Amherst, NY/Novi, MI, USA |
| Manual operated torque tools | 0.01 N⋅m | to | <1 N·m | |
| | 1 N·m | to | <5 N·m | Kistler Remscheid GmbH, Germany |
| | 5 N·m | to | 1.5 kN⋅m | |
| Mass and mass related | 1 bar | to | 250 bar | Amherst, NY/Novi, MI, USA |
| Mass, force and weighing devices | Force | | | |
| | | V compre | | Kistler Japan Co. Ltd, Shinyokohama, JP |
| | | V compre | | |
| | | V compre | | |
| | | V compre | 551011 | |
| | Moment | 0.0000 | ssion | |
| | | n compre | | |
| | | n compre | | |
| | 900 N·N | n compre | 551011 | |

| Measurand/Unit under test | | Range | | Laboratory, City, Country |
|---|-------------------|----------|---------------------|---|
| Multicomponent force and torque | 0.5 kN | to | 50 kN | |
| Addition of the second s | | | | Kistler ATD Heidelberg, Germany |
| Multicomponent transducers (ATD) | 2 N·m | to | 1 400 N⋅m | |
| Multicomponent force and torque | 2 kN | to | 50 kN | |
| Multicomponent transducers | 0.1 kN∙m | to | 10 kN⋅m | Kistler Instrumente GmbH Sindelfingen, |
| | | | | Germany |
| | 2 kN | to | 50 kN | |
| | 0.1 kN⋅m | to | 10 kN⋅m | |
| Pneumatic pressure Gage/absolute | –14.5 psi | to | <0 psi | Amherst, NY/Novi, MI, USA |
| Current: 4 mA to 20 mA | >0 psi | to | 1 500 psi | Annierst, NT/NOVI, MI, OSA |
| Pneumatic pressure | –14.5 psi | to | <0 psi | |
| Gage/absolute | >0 psi | to | 1 500 psi | Amherst, NY/Novi, MI, USA |
| Current: 4 mA to 20 mA | >0 psi | 10 | 1 200 þ31 | |
| Pneumatic pressure Gage/absolute | –14.5 psi | to | <0 psi | |
| Voltage: Up to 10 V | >0 psi | to | 1 500 psi | Amherst, NY/Novi, MI, USA |
| | 0 bar | | | |
| Positive pressure p _e | 0 bar 2 bar | to | 400 bar | |
| | 2 bar >400 bar | to to | 400 bar 1400 bar | Kistler Instrumente GmbH Sindelfingen, Germany |
| | >400 bar 0 bar | to to | 1400 bar 20 bar | Germany |
| Pressure | 1 bar | to | 20 Dai | |
| Absolute pressure p _{abs} | 3 bar | to | 401 bar | |
| Pabs | >401 bar | to | 1401 bar | Kistler Instrumente GmbH Sindelfingen, Germany |
| | 0 bar | to | 20 bar | Germany |
| Pressure | -14.5 psi | to | <0 psi | |
| Absolute | > 0 psi | to | <0 psi 500 psi | Amherst, NY/Novi, MI, USA |
| Pressure | | | | |
| Sinusodial | 50 psi | to | 1 000 psi | Amherst, NY/Novi, MI, USA |
| Pressure | 20 psi | to | 15 000 psi | |
| Static | 5 000 psi | to | 100 000 psi | Amherst, NY/Novi, MI, USA |
| Pressure | 1 bar | to | 300 bar | Ambarat NIX/Navi All LISA |
| Static | 80 bar | to | 8 000 bar | Amherst, NY/Novi, MI, USA |
| Rotational displacement | 0° | to | 360° | Amherst, NY/Novi, MI, USA |
| Time – measure | 0 µs | to | 150 µs | Amherst, NY/Novi, MI, USA |
| Torque on-site | 0.2 N·m | to | 1 kN·m | Kistler Demscheid CmbH. Cormony |
| Torque measuring systems | 200 N·m | to | 60 kN∙m | Kistler Remscheid GmbH, Germany |
| Torque sensors | 2 N⋅m | to | 10 N∙m | |
| | 10 N∙m | to | 200 N·m | |
| | 50 N∙m | to | 500 N∙m | Amherst, NY/Novi, MI, USA |
| | 500 N∙m | to | 2kN∙ m | |
| | 2 kN∙m | to | 4 kN∙m | |
| Torque wrench calibration systems | 0.2 N·m | to | <2 N·m | Kistler Remscheid GmbH, Germany |
| | 2 N·m | to | 3 kN∙m | Rister Refiscience Glibri, Germany |
| Torque wrench calibration systems | 0.2 N·m | to | <2 N·m | Kistler Remscheid GmbH, Germany |
| on-site | 2 N·m | to | 3 kN∙m | |

| Measurand/Unit under test | | Range | | Laboratory, City, Country |
|---|--------------------|-------|---------------------|---|
| Torque wrenches | 2 N·m | to | 20 N·m | |
| | >20 N⋅m | to | 500 N∙m | Amherst, NY/Novi, MI, USA |
| Torque | 0.01 N·m | to | <0.1 N·m | |
| Torque sensors and torque | 0.1 N⋅m | to | <1 N⋅m | |
| measuring equipment | 1 N⋅m | to | 1 kN⋅m | Kistler Remscheid GmbH, Germany |
| | >1 kN·m | to | 2 kN⋅m | |
| | >2 kN·m | to | 20 kN∙m | |
| Torque | 0.004 N⋅m | to | 0.01 N⋅m | |
| Torque sensors and torque | >0.01 N·m | to | <0.1 N∙m | |
| measuring chains | 0.1 N·m | to | 20 N∙m | |
| | 0.1 N·m | to | <0.2 N·m | |
| | 0.2 N⋅m | to | <0.4 N·m | |
| | 0.4 N·m | to | <1 N·m | |
| | 1 N⋅m | to | 200 N⋅m | |
| | 1 N·m | to | | Kistler Instrumente GmbH Lorch, Germany |
| | >10 N·m | to | 3 kN∙m | |
| | 1 N·m | to | 5 N·m | |
| | >5 N·m | to | 10 N·m | |
| | >10 N·m | to | 20 N·m | |
| | >20 N·m | to | 5 kN·m | |
| | 1 kN·m | to | 20 kN·m | |
| | >20 kN⋅m | to | 100 kN⋅m | |
| Transfer torque wrenches | 0.1 N·m | to | <1 N·m | Kistler Remscheid GmbH, Germany |
| | 1 N·m | to | 1 kN·m | |
| Velocity | 1 kph | to | 330 kph | Amherst, NY/Novi, MI, USA |
| Vibration Magnitude & charge/frequency response 10 Hz to 2 000 Hz | | | | |
| >2 000 Hz to 10 000 Hz | 5 mV | to | 4 V/gn | Amherst, NY/Novi, MI, USA |
| >10000 Hz to 15 000 Hz | 0.1 pC | to | 100 pC/gn | |
| >15 000 Hz to 17 000 Hz | | | | |
| >17 000 Hz to 20 000 Hz | | | | |
| Vibration, magnitude/frequency response | | | | |
| 3 Hz to 8 Hz | 0,04 mV | to | 4 V/gn | |
| >8 Hz to 16 Hz | at 100 Hz | | | Amherst, NY/Novi, MI, USA |
| >16 Hz to 1 000 Hz >1 000 Hz to 5 000 Hz | 0,1 pC | to | 100 pC/gn | |
| >5 000 Hz to 10 000 Hz | | | 1 0 | |
| Vibration, magnitude/frequency 0.5 Hz to 20 Hz | 5 mV | to | 4 V/gn | Amherst, NY / Novi, MN, USA |
| Vibration calibrator | 1 m/s ² | to | 20 m/s ² | Kistler Instrumente GmbH Sindelfingen, Germany |
| Vibration, rotational (magnitude) | 12.5 Hz | | | Amherst, NY/Novi, MI, USA |
| Voltage Voltage measuring amplifier with grounded input and differential input, ICP-Measuring amplifier with constant current supply | 70 mV | to | 30 V | Kistler Instrumente GmbH Sindelfingen, Germany |
| Voltage Current resistance ratio Piezo resistive amplifiers | 10 Ω | to | 1 000 Ω | Amherst, NY/Novi, MI, USA |

Would you like to learn more about our applications? Explore now:



www.kistler.com

Kistler Group Eulachstrasse 22 8408 Winterthur Switzerland Tel. +41 52 224 11 11

Kistler Group products are protected by various intellectual property rights. For more details, visit **www.kistler.com** The Kistler Group includes Kistler Holding AG and all its subsidiaries in Europe, Asia, the Americas and Australia.

Find your local contact at **www.kistler.com**

